
Scanning Electron Microscopy (SEM)



Leibniz Institute
for high
performance
microelectronics

Technical Parameters

SEM System:

Zeiss MERLIN Gemini 2

Primary Beam: Electrons 1 - 25 kV

Signal Detectors:

- secondary electron detector (SE , In-Lens)
- energy-selective backscattered electron detector (ESB , In-Lens)
- backscattered electron detector (BSD)

Lateral Resolution:

- 2.0 nm @ 25 kV
- 2.5 nm @ 1 kV



Application areas

- high resolution SEM images

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